Biological Removal of Copper & Organic Contaminants from Chemical-Mechanical Planarization (CMP) Effluents



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Thrust C: Factory Integration

Task C-1: Novel Processes for Water Purification and Wastewater Treatment

Subtask C-1-2:

Bio-treatment of Waste Streams Containing Organic Compounds and Copper





Cu interconnect technology is rapidly replacing traditional processes for the metallization of semiconductor devices





<u>Cu-Chemical Mechanical Planarization</u> (<u>CMP</u>) effluents ~ 30-40% water consumed in a fab

Cu-CMP effluents contain significant quantities of soluble <u>copper</u> and <u>organic contaminants</u>

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CMP Wastewater Components

<u>Inorganic</u>

Copper: Inorganic solids: Oxidizers, strong acids/bases: Soluble Cu⁺² (1-50 mg/l) Abrasives (eg. SiO₂, Al₂O₃, CeO₂) H_2O_2 , NO₃⁻, KMnO₄, HF, NH₃, OH⁻, etc

<u>Organic</u>

Metal chelators / acids: Corrosion inhibitors: Surfactants/dispersants: Citric acid, oxalic acid, EDTA, peroxy acetic, etc. Benzotriazoles PFOS, alkyl sulfates, etc.

Source: Golden et al. 2000. Semiconductor Int. 23: 85-98.

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Why Treat CMP Effluents?

To meet environmental standards; eg:

Cu limit : - discharge to POTWs: 1- 2 mg Cu/l - direct discharge: 5-10 µg Cu/l

Enable water reuse

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Treatment of CMP Effluents: Physico-Chemical Methods



(Removal of solids, metals, fluoride, soluble silica)

Requires large tanks, high chemical addition Generates (toxic) sludges High residual Cu and suspended solids content

UF / oxidant removal/ lon exchange (Removal of solids, oxidants, copper)

Expensive; No removal of organic fraction

Bioremediation of Heavy Metals



Environmental biotechnologies offer interesting potentials for metal removal and recovery (Zn⁺², Pb⁺²; Se(V); U(VI), etc.)



Biological treatment could also provide an attractive approach to effectively meet regulatory challenges associated with Cu-CMP.

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Anaerobic Biotechnology



Expanded Granular Sludge Bed (EGSB) reactors

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High-Rate Bioreactors



Biological Wastewater Treatment System at Philips,

(Stadskanaal, The Netherlands) for the removal of heavy metals (Ni, Pb, Cr, Al, Fe), nitrate and acetate.

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Removal of Metal by Sulfate Reducing Bacteria (SRB)

$$SO_4^{2-} + 4 H_2 + H^+ \longrightarrow HS^- + 4 H_2O$$
(Electron donor)
$$S = + M^{2+} \longrightarrow MS \downarrow$$
Metal Sulfide

Metal Sulfides: very low solubility products (K_{sp}) eg. 10⁻⁴⁹ for CuS

Biologically Formed ZnS in a Sulfate Reducing Biofilm

Labrenz et al. 2000 Sience 290:5497



Treatment of Heavy-Metal Containing Wastewaters in Single-phase Anaerobic Sulfidogenic Bioreactors

Advantages

- Very low effluent Cu concentrations
- Simultaneous removal of organics
- Low maintenance & operational costs (low energy input / chemical requirements)
 - Rapid application at the industrial scale due to widespread full-scale experience with core technology

Drawbacks

- Possible microbial inhibition by heavy metals
- Contamination of biosolids with heavy metals
- Selective recovery of Cu not feasible

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Anaerobic Sulfate Reducing Bioreactor –

Crystallization Reactor (ASBR-CR)



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Research Objectives

Investigate the feasibility of a novel treatment system consisting of an **anaerobic sulfate-reducing bioreactor – crystallization reactor** for the simultaneous removal of copper and organic contaminants in CMP effluents.



Susceptibility of CMP wastewater components to anaerobic biodegradation



Inhibitory effects of CMP wastewater components to anaerobic microorganisms



Evaluate the treatment of CMP effluent containing varying Cu levels in the two-reactor system

Results - Microbial Inhibition

		IC ₅₀
Compound	Structure	(mg/l)
Copper (II)	Cu	20.6 mg/l
Benzotriazole [BTA]		NT (<310 mg/l)
Poly(ethylene glycol) [PEG]	$H - (O CH_2 CH_2 -)_n OH$	NT (<349 mg/l)
PEG monooleate [PEG-mono]	$\begin{array}{c} H \\ c = c \\ H_{2} \\ c + c \\ c \\$	NT (<1000 mg/l)
Perfluoro-1-octanesulfonic acid tetraethylammonium salt [PFOS]	$\begin{array}{c} CF_3(CF_2)_6CF_2-\overset{O}{\underset{S}{\overset{I}}{\overset{I}{\overset{I}{\overset{I}}{\overset{I}{\overset{I}{\overset{I}}{\overset{I}{\overset{I}{\overset{I}{\overset{I}{\overset{I}{\overset{I}{\overset{I}{\overset{I}{\overset{I}}{\overset{I}}{\overset{I}{\overset{I}}}}}}}}}$	NT (<612 mg/l)
Citric Acid	СООН СООН СООН H2CСH2 ОН	NT (<1237 mg/l)

NT - Non-toxic at concentrations less than the maximum tested concentration, as indicated

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Anaerobic Biodegradability



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Anaerobic Biodegradability

	Biodegradability		
Compound	Methanogens	SRB	
Polyethylene glycol	Yes	Yes	
Polyethylene glycol monooleate	Yes	Yes	
Isopropyl alcohol	Yes	Yes	
Citric Acid	Yes	Yes	
Oxalic acid	Partial	Yes	
Triton X-100	No	Yes	
Fluorinated Surfactant (PFOS)	No	No	
Benzotriazole	No	No	
Hydro-benzotriazole	No	No	

SRB - Sulfate Reducing Bacteria

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Anaerobic Sulfate-Reducing Bioreactor – Crystallization Reactor System



Schematic representation of the anaerobic bioreactor - crystallization reactor system

- 1 Influent
- 2 Crystallization reactor (CR)
- 3 Effluent CR
- 4 Mesophilic bioreactor (MR)
- 5 Gas cap
- 6 Biogas
- 7 Safety flask
- 8 Sodium hydroxide
- 9 Gasmeter
- 10 Liquid effluent recirculation
- 11 Liquid effluent

Τ=	30°C
HRT =	8 h
Recycle ratio =	15
Influent COD =	3 g/l
COD/sulfate =	0.55
Cu conc. =	0-65 mg/l

Anaerobic Sulfate-reducing Bioreactor





Electron scanning micrograph of microorganisms in the anaerobic biofilms

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Experimental periods

Period	Cu(II) (mg/l)	Organic matter (g COD/I)		
l l	0	3	(ethanol)	
ll II	0	3	(simulated	I CMP waste)*
III	5	3	"	£ 6
IV	25	3	"	66
V	65	3	"	"

* Simulated CMP waste:

Citric acid / poly(ethylene glycol) (PEG Mn=400) /isopropanol (IPA) (1 g COD/L each)

Organic Removal



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Cu Concentrations in the Effluent of the Two-reactor System and the Effluent of the Crystallization Reactor









Detail of the crystallization reactor during the first day (*left*) and after 5 days of operation (*right*) with an influent containing 5 mg Cu/l.

SEM Images of Crystallization Sand



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SEM-EDS Analysis of Sand



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System Performance: Removal of Organic Contaminants

Influent	COD removal (%)	
Ethanol	94.7 +/- 3.0	
Simulated CMP	66.8 +/- 9.8	
Simulated CMP + 5 mg Cu/l	65.7 +/- 8.1	
Simulated CMP + 25 mg Cu/l	60.4 +/- 7.4	
Simulated CMP + 75 mg Cu/l	66.6 +/- 7.5	

Organic loading rate: 9.1-10.6 g COD/I/day

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System Performance:

Copper Removal

Period	Cu ²⁺ -in (µg/l)	Cu ²⁺ -out (µg/l)	Cu removal (%)	Cu Removal (%) CR only
III	5,000	16 (+/- 19)	99.4 (+/-1.3)	99.3 (+/-0.6)
IV	25,000	162 (+/-84)	99.3 (+/-0.5)	99.3 (+/- 0.2)
V	65,000	104 (+/- 45)	99.9 (+/-0.2)	99.8 (+/- 0.1)

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Conclusions



Results from batch bioassays indicated that <u>typical components in</u> <u>CMP effluents were amenable to anaerobic treatment</u>

The proposed system was shown to be <u>highly effective to remove Cu</u> from a simulated CMP wastewater.

Very high Cu removal efficiencies (99.4-99.9% soluble Cu) were obtained for wastewaters containing 5-65 mg Cu/L.

Elimination of total copper ranged 88.6-97.3%.



<u>Cu removal occurred chiefly in the crystallization reactor</u> as a result of copper sulfide precipitation onto the sand surface



Low removal efficiencies of IPA and acetone resulted in incomplete COD removal

Future Research



Optimize the removal of Cu and organic contaminants



Determine the maximum Cu loading capacity of CR packing material

Develop a model for the CR to assist with predicting and improving Cu removal rates and efficiencies



Evaluate methods for metal recovery from the sand particles and evaluate potential for bed regeneration



Evaluate performance of the bioreactor - CR system treating actual CMP wastewater

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